

RECEIVED
CENTRAL FAX CENTER

APR 03 2006

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Group Art Unit: 2818
Examiner: Chuong A. Luu
Confirmation No.: 6341

In Re PATENT APPLICATION Of:

Applicant: Noriko Tomita et al.

)

Serial No.: 10/660,490

)

Filed: September 12, 2003

)

For: SEMICONDUCTOR SUBSTRATE
SURFACE PROTECTION METHOD

) AMENDMENT

Attny Ref.: OHG 135

)

) and

) PETITION for extension of time

)

)

)

April 3, 2006

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

This paper is in response to the Official Action mailed on December 2, 2005. Payment for one month's extension of time is attached. Please charge our Deposit Account No. 18-0002 if any additional fees are needed to enter this paper, and please advise us accordingly. It is noted that no petition is required because of the authorization to charge, but this paper is a petition for extension of time.

The amendment to recite "leaving the substrate to stand in air containing ambient organic substances" is supported in claim 20, in the specification at page 1, line 26 to page 2, line 3, and in claim 23 (the word "ambient").

I certify that this correspondence is being facsimile transmitted to the United States Patent and Trademark Office (fax no. 571-273-8300) on April 3, 2006.

Nick Bromer [reg. no. 33,478]

Nick Bromer
Signature